



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of Chang Gyu KIM et al.	) METHOD FOR FORMING ISOLATION ) LAYER OF SEMICONDUCTOR DEVICE
Korean Application No. 2001-15415	) LATER OF SEMICONDUCTOR DEVICE )
Korean Filing Date: March 24, 2001	) Group Art Unit: 2823
Serial No.: 10/001,314	) Examiner: N. Berezny )
Filed: November 14, 2001	) )
Commissioner for Patents P.O. Box 1450 Alexandria VA 22313-1450	RECEIVEL OCT 23 2003 TECHNOLOGY CENTER 2
Alexandra VA 22313-1430	2800

## **AMENDMENT**

Sir:

In response to the Office action of June 16, 2003, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.